Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	134	schellenberg.in.	USPAT	OR	OFF	2005/01/13 08:20
S2	10	S1 and franklin	USPAT	OR	OFF	2005/01/13 08:51
S4	55	optical near process near correction	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 08:52
S5	52	S4 and (mask or reticle)	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 08:52
S6	9	S5 and (etch near (effect or distortion or bias or correction))	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:18
S7	666	703/13.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:18
S8	2	S7 and (optical near process near correction)	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:20
S9	0	S7 and (etch near (effect or distortion or bias or correction))	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:20
S10	3141	716/4,8,19.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:20
S11	28	S10 and (optical near process near correction)	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:21
S12	6	S11 and (etch near (effect or distortion or bias or correction))	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/01/13 09:21
S13	2	("5682323"|"5801954").PN.	USPAT	OR	OFF	2005/01/13 10:01
S14	1	("6425113").PN.	USPAT	OR	OFF	2005/01/13 10:39
S15	506	"optical proximity correction"	USPAT	OR	OFF	2005/01/13 10:40
S16	202	S15 and etch	USPAT	OR	OFF	2005/01/13 10:40
S17	117	S16 and simulat$3	USPAT	OR	OFF	2005/01/13 10:40
S18	116	S17 and (mask or retile or layout)	USPAT	OR	OFF	2005/01/13 10:41
S19	104	S18 and lithograph$6	USPAT	OR	OFF	2005/01/13 10:42